
ERRATUM

Erratum to: “Near-Field Optical Lithography in Application to Plasmonic Antennas Characterization” [Instruments and Experimental Techniques 59, 837 (2016)]

A. V. Shelaev^{a*}, P. S. Dorozhkin^{a, b}, and V. A. Bykov^a

^a *NT-MDT Co., build. 317-A, PO box 158, Zelenograd, Moscow, 124482 Russia*

^b *Skolkovo Institute of Science and Technology, Skolkovo Innovation Center, ul. Nobelya 3, Moscow, 143026 Russia*

**e-mail: shelaev@ntmdt.ru*

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